



IRW

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Noriyoshi SATO et al.

Group Art Unit: 2891

Application No.: 10/539,569

Examiner: C. EVERHART

Filed: August 18, 2005

Docket No.: 124305

For: PLASMA GENERATOR, OZONE GENERATOR, SUBSTRATE PROCESSING
APPARATUS AND METHOD OF MANUFACTURING SEMICONDUCTOR
DEVICE

STATEMENT OF SUBSTANCE OF THE INTERVIEW

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

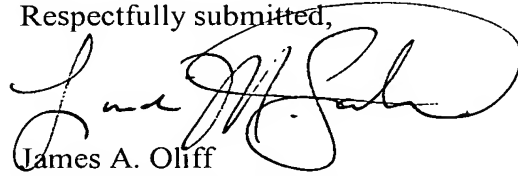
Sir:

Applicants appreciate the courtesies shown to Applicants' representatives by Examiner Everhart in the September 5 personal interview. Applicants' separate record of the substance of the interview is incorporated into the following remarks.

During the interview, Applicants' representatives presented arguments corresponding to Applicants' Request for Reconsideration filed on August 29, 2008. Applicants' representatives ensured that the Examiner understood the presently claimed subject matter and explained to the Examiner the deficiencies in the applied references.

Should any questions arise regarding this submission, all inquiries may be directed to Applicant's undersigned representatives at the telephone number set forth below.

Respectfully submitted,



James A. Oliff

Registration No. 27,075

Linda M. Saltiel

Registration No. 51,122

JAO:LMS/dqs

Date: September 9, 2008

OLIFF & BERRIDGE, PLC
P.O. Box 320850
Alexandria, Virginia 22320-4850
Telephone: (703) 836-6400

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